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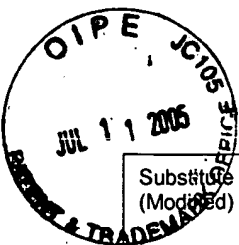
Respectfully submitted,

Date: July 6, 2005

  
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Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-882001	Application No. 10/693,373
<b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary)  (37 CFR §1.98(b))		Applicant <b>Yan Borodovsky</b>	
		Filing Date October 24, 2003	Group Art Unit 1756

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	5,759,744	June 2, 1998	Brueck, et al.			
	AB	5,415,835	May 16, 1995	Brueck, et al.			
	AC	5,328,807	July 12, 1994	Tanaka, et al.			
	AD	6,553,562	April 22, 2003	Capodieci, et al.			
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AL	EP 0855623	July 29, 1998	EP				
	AM	WO 98/32054	July 23, 1998	PCT				
	AN							
	AO							
	AP							

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	AQ	Ishibashi, et al., "AFM Lithography Combined with Optical Lithography", <i>IEEE Microprocesses and Nanotechnology Conference 2000</i> , pp. 192-193 (July 2000).
	AR	Martin, et al., "Ordered Magnetic Nanostructures: Fabrication and Properties", <i>J. Magnetism and Magnetic Materials</i> , 256(1-3):449-501 (January 2003).
	AS	
	AT	

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	